

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 66302-006US1	Application No. 10/536,512
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)  (37 CFR §1.98(b))		Applicant Jae-Hyun Kim	
		Filing Date May 25, 2005	Group Art Unit 1752

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
/SL/	AA	6,033,830	03/07/2000	Sinta et al.	430	325	
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
/SL/	AL	WO00/54105	09/14/2000	WIPO				
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
/SL/	AQ	Hwang S-H et al., "A novel organic bottom anti-reflective coating material for 193nm excimer laser lithography," Polymer, Elsevier Science Publishers B.V, GB, Vol. 41, No 17, August 2000 (2000-08), pages 6691-6694, XP004196891.
	AR	
	AS	
	AT	

Examiner Signature /Sin Lee/	Date Considered 02/15/2008
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